



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Reissue Application of: )

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Inventor: Kiichi HAMA et al. )

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For: PLASMA PROCESS  
APPARATUS )

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Examiner: L. Alejandro Mulero

Commissioner for Patents  
Washington, DC 20231

Sir:

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APPENDIX TO AMENDMENT FILED MAY 9, 2002

IN THE CLAIMS:

124. (Twice Amended) The apparatus according to claim [123] 120, wherein  
said inactive gas supplied into said auxiliary container portion is a coolant, by which said  
planar spiral coil is cooled.

137. (Amended) The apparatus according to claim [123] 120, wherein said  
pressure controller controls an output of said exhaust pump according to an amount of  
inactive gas supplied by said auxiliary supply.